

IN THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-12 Cancelled

13. (currently amended) A chemical mechanical planarization (CMP) system, comprising:

a first brush having a CMP pad covering an outer portion of the first brush;

a second brush, the second brush being oriented relative to the first brush to receive a wafer between the first and second brushes;

a first drive roller;

a second drive roller, the first and second drive rollers being configured to receive an edge of the wafer to stabilize and rotate the wafer when placed between the first and second brushes; and

a slurry dispenser disposed above the two drive rollers, the slurry dispenser being configured to dispense slurry onto the surface of the wafer.

14. (original) The CMP system of claim 13, further comprising:

a third drive roller, the first, second, and third drive rollers being configured to receive an edge of the wafer to stabilize and rotate the wafer when placed between the first and second brushes.

15. (original) The CMP system of claim 13, further comprising:

a housing, the housing being configured to enclose the CMP system.

16. (currently amended) The CMP system of claim 13, ~~further comprising: a~~
~~CMP pad covering an outer portion of the first brush~~ wherein the first brush and the second
brush apply a pressure between about 1 pound per square inch and about 6 pounds per square
inch to corresponding surfaces of the wafer.

17. (original) The CMP system of claim 16, wherein the CMP pad includes:

a cylindrical core; and

a CMP pad material disposed on an outer portion of the cylindrical core.

18. (original) The CMP system of claim 17, wherein the CMP pad material is
configured for buffing.

19. (original) The CMP system of claim 17, wherein the CMP pad material is
comprised of porous rubber.

20. (original) The CMP system of claim 17, wherein the CMP pad material is
configured for cleaning.

21. (original) The CMP system of claim 13, wherein the first and second brushes
are comprised of polyvinyl alcohol (PVA).

22. Cancelled